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elSBN: 978-1-60805-359-9

Semiconductor Strain Metrology Principles and Applications

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About the ebook

This book surveys the major and newly developed techniques for semiconductor strain metrology. This e-book employs a tutorial approach to explain the principles and applications of each technique specifically tailored for graduate students and postdoctoral researchers.

Contents

- Introduction to Strain Metrology for Semiconductors
- Strain, Stress and Semiconductor Properties
- PART 2: OPTICAL STRAIN METROLOGY
- Variable Angle Spectroscopic Ellipsometry
- Photoreflectance Method
- Micro-Raman Spectroscopy
- PART 3: ELECTRON BEAM STRAIN METROLOGY
- Cathodoluminescence Method

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